

AMENDMENTS TO THE CLAIMS

1-5. (Cancelled)

6. (Currently Amended) A method for manufacturing a plasma display panel (PDP) including a process for forming a metal oxide film onto a substrate of the PDP, the method comprising:

introducing inert gas into a deposition room during deposition of the metal oxide film;

introducing oxygen into the deposition room during deposition of the metal oxide film ~~so as to reduce an oxygen deficiency in the metal oxide film;~~

introducing at least one gas selected from the group consisting of carbon monoxide and carbon dioxide into the deposition room during deposition of the metal oxide film ~~so as to increase the oxygen deficiency in the metal oxide film,~~ wherein the oxygen ~~or~~ and the at least one gas ~~is~~ are introduced into the deposition room in a predetermined amount;

controlling an amount of dangling bonds in the metal oxide film ~~amounts of at least one of the inert gas and the other of the oxygen or the at least one gas to be introduced into the deposition room;~~ and

equilibrating the amounts of the gasses introduced into the deposition room with an amount of gas exhausted from the deposition room by a vacuum exhausting system so as to ~~control the oxygen deficiency within a predetermined range and~~ maintain a degree of vacuum in the deposition room within a range of 1×10^{-1} Pa to 1×10^{-2} Pa, wherein said equilibrating of the amounts comprises adjusting an amount of the inert gas introduced into the deposition room.

7. (Currently Amended) The method for manufacturing the PDP of claim 6, wherein said introducing of the at least one gas comprises introducing at least one gas selected from the group consisting of carbon monoxide and carbon dioxide at a constant amount into the deposition room, and

wherein said controlling of the ~~amounts~~ amount of dangling bonds comprises adjusting an amount of the oxygen gas introduced into the deposition room.

8. (Currently Amended) The method for manufacturing the PDP of claim 6, wherein said introducing of oxygen comprises introducing an amount of oxygen at a constant value, and

wherein said controlling of the ~~amounts~~ amount of dangling bonds comprises adjusting an amount of the at least one gas selected from the group consisting of carbon monoxide and carbon dioxide introduced into the deposition room.

9-10. (Cancelled)